



Attorney's Docket No.: 05542-450001 / 4563-3/CMP

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5-14-03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Fritz Redeker et al.
Serial No. : 09/918,591
Filed : July 27, 2003

Art Unit : 2812
Examiner : Angel Roman
Confirmation No.: 2013
Notice of Allowance Date: 03/10/2003

Title : CHEMICAL MECHANICAL POLISHING OF A METAL LAYER WITH
POLISHING RATE MONITORING

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Commissioner for Patents
Washington, D.C. 20231

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

Applicant respectfully notes that other reasons for patentability may exist, and that not all of the limitations noted by the Examiner may be required for patentability.

Applicant also notes that the claims do not recite the exact wording used by the Examiner. In particular, the Examiner mentions the limitations of "monitoring polishing at a lower rate ... after monitoring polishing at a higher rate." In contrast, claim 1 calls for polishing the metal layer at a second polishing rate that is lower than the first polishing rate, and claims 8 and 14 call for reducing the polishing rate.

Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 4/15/03

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CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, Washington, D.C. 20231.

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